03500.017731

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	Examiner: Not Yet Assigned Group Art Unit: Not Yet Assigned
HIDEYA KUMOMI ET AL.	
Application No.: Not Yet Assigned	
International Appln. No.: PCT/JP03/15072	:)
International Filing Date: November 26, 2003)
Filed: Herewith	·)
For: PRODUCING METHOD FOR CRYSTALLINE THIN FILM	:) : April 27, 2005

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed Form PTO-1449. Copies of the listed foreign and published technical documents are also enclosed.

The concise explanation of relevance for the non-English documents is found in an attached abstract and, if provided, in a corresponding U.S. Patent.

Corresponding U.S. patents and published applications for foreign patent documents in the English language are provided, where available.

CONCLUSION

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our address given below.

Respectfully submitted,

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JC12 Rec'd PCT/PTC 28 APR 2005 APPLICATION NO.: National Stage of PCT/sP0/607/5 3 3 0 9 1 FORM PTO 1449 (modified) ATTY DOCKET NO. 03500.017731 U.S. DEPARTMENT OF COMMINION PATENT AND TRADEMARK OFFICE HIDEYA KUMOMI APPLICANT: LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary) FILING DATE **GROUP** NYA Herewith U.S. PATENT DOCUMENTS *EXAMINER INITIAL DOCUMENT NUMBER FILING DATE DATE NAME CLASS SUBCLASS 148 4,564,403 1/1986 Hayafuji et al. 171 4,670,088 6/1987 Tsaur et al. 156 617 5,021,119 6/1991 Fan et al. 5,318,661 6/1994 Kumomi et al. 9/1995 Fan et al. 5.453.153 5,496,768 3/1996 Kudo, T. 437 174 12/2001 6.326,286 Park et al. 2003/003766 1/2003 Kumomi et al. FOREIGN PATENT DOCUMENTS **TRANSLATION** DOCUMENT NUMBER DATE YES/NO/ OR ABSTRACT COUNTRY **CLASS SUBCLASS** GB Corresp to 2338342 12/199 **United Kingdom** USP 6,326,286 **EP** Corresp to 0472970 3/1992 **Europe** USP 5,318,661 EP Corresp. to 1262578 12/2002 **Europe** 2003/003766 WO Corresp. to 89/04550 5/1989 **PCT** UPS 5,021,119 and 5,453,153 OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.) Kuriyama et al., "Comprehensive Study ... Thin Film Transistors", Jpn. J. Appl. Phys., Vol. 33. (Part 1, No. 10) (1994) 5657-5662. Van Der Wilt, "Grain Location ... Thin Silicon Film", Phys. Stat. Solidi Vol. 166 No. 2, 619-626 (April 1998). Kumomi et al., "Manipulation of nucleation sites ... Si Crystallization", Appl. Phys. Ltts., Vol. 59, No. 27, 3565-3567 (Dec. 1999). Hatano et al.; "In situ and ex situ ... laser annealing", J. Non-Cryst. Solids, Vol. 266-269, 654-658 (May 2000) Patent Abstracts of Japan, Vol. 0080, No. 52 (C-213) 3-1984 for JP 58-208297 Patent Abstracts of Japan, Vol. 0172, No. 53 (E-1367) 5-1993 for JP04-373171

EXAMINER

Patent Abstracts of Japan, Vol. 0164, No. 99 (E-1290) 10-1992 for JP04-184918

DATE CONSIDERED